AMENDMENT UNDER 37 C.F.R. § 1.111

Appln. No.: 09/849,886

Attorney Docket No.: Q64212

allow the processing medium to form a thin film, the electrode and the processing subject

defining a contact area therebetween;

moving at least one of the electrode and the processing subject relative to each other with

a relative shifting rate, and

controlling a thickness of the film by changing at least one of parameters of the contact

area between the electrode and the processing subject, the pressing pressure and the relative

shifting rate and the viscosity of the processing medium.

8. (Amended) The discharge processing method according to claim 1, wherein a green

compact, which is formed by compressing and molding metal that forms a compound or powder

thereof, is used as the electrode, and a processing medium containing carbon is used as the

processing medium.

13. (Amended) A discharge processing device, wherein an insulating processing

medium having a viscosity is interposed between an electrode and a processing subject and

discharging energy is supplied between the electrode and the processing subject so that the

processing subject is processed by the discharge, comprising:

a pressing unit which presses an electrode against a processing subject with a

predetermined pressure so as to allow the processing medium to form a thin film, the electrode

and the processing subject defining a contact area therebetween;

a driving unit which moves the electrode and the processing subject relative to

each other with a relative shifting rate; and

a control unit which controls the contact area between the electrode and the processing

-2-

AMENDMENT UNDER 37 C.F.R. § 1.111

Appln. No.: 09/849,886

subject, the pressing pressure, the relative shifting rate and the viscosity of the processing medium as parameters, and gives an instruction for changing at least one of the pressing pressure and the relative shifting rate so that a thickness of the film is controlled.

Attorney Docket No.: Q64212

- 14. (Amended) The discharge processing device according to claim 13, wherein the thin film has a thickness of 0.1 to $1 \mu m$.
- 15. (Amended) The discharge processing device according to claim 13, wherein a trace of the relative movement is spiral.
- 16. (Amended) The discharge processing device according to claim 13, wherein the processing medium is a lubricant.
- 17. (Amended) The discharge processing device according to claim 13, wherein the processing medium is grease.
- 18. (Amended) The discharge processing device according to claim 13, wherein the processing medium is a material formed by allowing a polymeric water absorber to absorb water.
- 19. (Amended) The discharge processing device according to claim 13, wherein the processing medium is a mixture containing silicon powder.
- 20. (Amended) The discharge processing device according to claim 13, wherein the electrode is a green compact, which is formed by compressing and molding a metal that forms a compound or a powder thereof, and the processing medium contains carbon.